

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:	)	Group Art Unit: 2822
Koichiro TANAKA et al.	)	Examiner: Mary A. Wilczewski
Serial No. 10/749,505	)	
Filed: January 2, 2004	)	
For: LASER IRRADIATION METHOD,	)	
METHOD FOR MANUFACTURING	)	
SEMICONDUCTOR DEVICE, AND	)	
LASER IRRADIATION SYSTEM	)	

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**OCT 31 2007**  
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**AMENDMENT**

Honorable Commissioner of Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

Please consider the following amendments and remarks in connection with the above-identified application.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper.

**Remarks** begin on page 14 of this paper.